

DOCKET NO.: 296428US26PCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Tsuyoshi TAKAHASHI, et al.

SERIAL NO.: NEW U.S. PCT APPLICATION

FILED: HERewith

INTERNATIONAL APPLICATION NO.: PCT/JP05/06158

INTERNATIONAL FILING DATE: March 30, 2005

FOR: METHOD AND APPARATUS FOR FORMING METAL SILICATE FILM, AND
METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE

**REQUEST FOR PRIORITY UNDER 35 U.S.C. 119
AND THE INTERNATIONAL CONVENTION**

Commissioner for Patents
Alexandria, Virginia 22313

Sir:

In the matter of the above-identified application for patent, notice is hereby given that
the applicant claims as priority:

<u>COUNTRY</u>	<u>APPLICATION NO</u>	<u>DAY/MONTH/YEAR</u>
Japan	2004-105300	31 March 2004

Certified copies of the corresponding Convention application(s) were submitted to the
International Bureau in PCT Application No. PCT/JP05/06158. Receipt of the certified
copy(s) by the International Bureau in a timely manner under PCT Rule 17.1(a) has been
acknowledged as evidenced by the attached PCT/IB/304.

Respectfully submitted,
OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



Steven P. Weihrouch
Attorney of Record
Registration No. 32,829
Surinder Sachar
Registration No. 34,423

Customer Number
22850

(703) 413-3000
Fax No. (703) 413-2220
(OSMMN 08/03)